

OMNI Point-of-Use Gas Purifier Systems



FEATURES

- ◆ Integral purifier, heater, insulation and electronics assembly
- ◆ Compact design
- ◆ Easy-to-use
- ◆ Sub-ppb removal of impurities from Inert Gases, Hydrogen, Acid Gases, and Oxygen
- ◆ Certified temperature control unit and electronics designed for simple operation, reliability and safety
- ◆ Continual heated operation or room temperature operation with convenient in-situ operation

APPLICATIONS

- ◆ Analyzers (Zero/Calibration Gases)
- ◆ Analytical Carts
- ◆ Process Tools
- ◆ Research and Development
- ◆ Semiconductor Industry

The NuPure™ Omni series of Point-of-Use purifier systems incorporate the UltraPure® PF series® purifier-filter or UltraPure® XL series purifier, reducing gaseous impurities, (see chart below) to sub-ppb levels from Inert Gases, Hydrogen and Hydrides, Acid Gases and Oxygen. The PF series® includes particle filtration to 0.003 µm. The NuPure™ Purifier Systems are available in a standard range of 0 - 100 slpm.

The NuPure™ Omni Series is available in a wall mounted configuration offering a low cost fully integrated system including manual inlet, outlet and bypass valves, and optional gas particle filter.

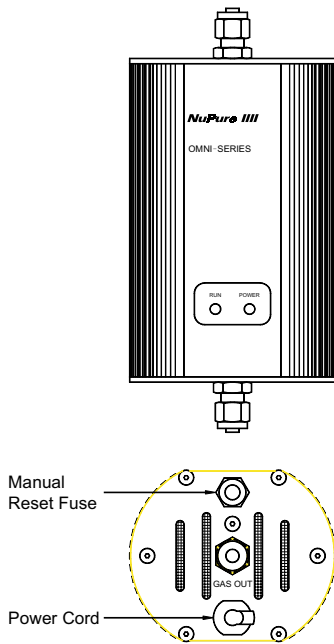
LISTING OF GASES PURIFIED / FILTERED

Inert Gases		Hydrogen / Hydrides		Acid Gases	Oxygen
Impurities Removed H ₂ O, O ₂ , CO, CO ₂ , H ₂ ¹ (N ₂ , CH ₄) ²		Impurities Removed H ₂ O, O ₂ , CO ₂ , CO, (N ₂) ³		Impurities Removed H ₂ O	Impurities Removed H ₂ O, CO ₂ , (H ₂ , CO, CH ₄) ⁴
Ar	Ar/CH ₄	H ₂	AsH ₃	HBr	O ₂
He	CH ₄	Ar/H ₂	PH ₃	HCl	Air
Ne	CF ₄	N ₂ /H ₂	NH ₃	BCl ₃	N ₂ O
Kr	CCl ₄	SiH ₄	B ₂ H ₆	BF ₃	
Xe	SF ₆	Si ₂ H ₆	H ₂ Se	Cl ₂	
N ₂	Freons	D.C.S.	GeH ₄	HF	

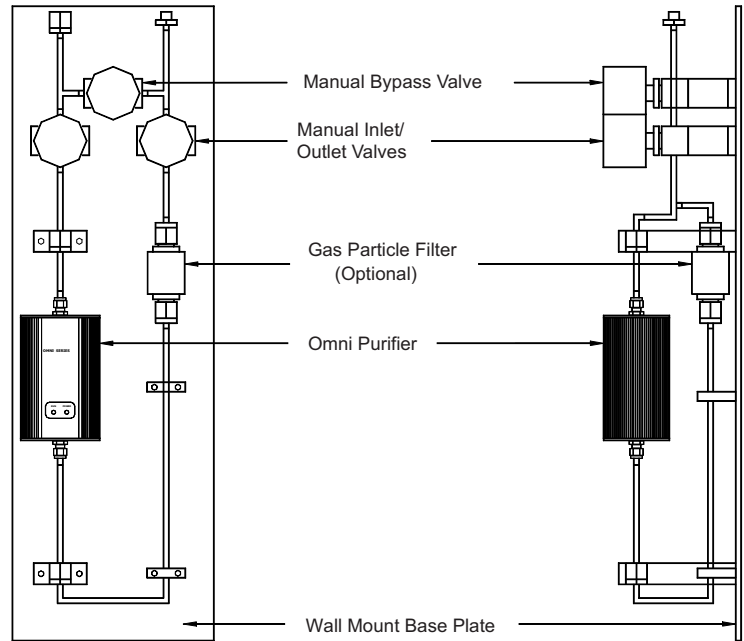
1 - Only with purchase of -H model. 2 - Additional impurities removed from He, Ne, Ar, Kr, Xe and N₂ only, using heated getter. 3 - Additional impurities removed from Hydrogen only, using heated getter. 4 - Only with purchase of optional heated catalyst.

NuPure™ Omni Series Point-of-Use Purifier

Technical Specification



Omni Series Purifier Module



Omni Series Purifier System

Model	Average Flows (slpm) ¹ for 1 year lifetime (removal of impurities per chart page 1)	Max Flow (slpm) @ 150 psig (Heated)	Voltage	115/240 V AC
Omni 40	0.3	1.5	Housing	Extruded Aluminium 6063
Omni 100	1	5	Maximum Pressure	250 psig/9.9 kg/cm ² G (Japan)
Omni 200	2	10	Operating Temperature	375°C - 450°C
Omni 600	6	30	Leak Rate	< 2 x 10 ⁻¹⁰ atm cc/sec He
Omni 1000	10	50	Materials (Purifier)	316L S.S. (< 10Ra)
Omni 2000	20	100	Fittings	1/4" VCR ² / Compression
			Gas Inlet	VLSI grade (99.9995%)

1 - Lifetime is inversely proportional to the total inlet impurity level and to the average flow. Lifetime for H₂O/O₂ removal only using getter purifiers is approx 4 years at the stated flows / inlet gas. Under nominal conditions.
 2 - VCR compatible fitting standard. VCR[®] is a registered trademark of Cajon Corporation.

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